Comments and Corrections

Corrections to "Device Linearity Comparison of Uniformly Doped and δ -Doped In_{0.52}Al_{0.48}As/In_{0.6}Ga_{0.4}As Metamorphic HEMTs"

Y. C. Lin, Edward Yi Chang, H. Yamaguchi, Y. Hirayama, X. Y. Chang, and C. Y. Chang

In the above paper, [1], Table I was incorrect. The correct table is printed below.

TABLE I Comparison of the DC Characteristics of the Uniformly Doped and the δ -Doped In_{0.52}Al_{0.48}As/In_{0.6}Ga_{0.4}As MHEMTs

	δ doped	Uniformly-doped
Device Type	In _{0.6} Ga _{0.4} As MHEMT	In0.6Ga0.4As MHEMT
I _{DSS} (I _{DS} @ V _{GS} =0, mA/mm)	414.5	228.0
Gm _{max} (mS/mm)	506.0	401.4
Pinch off voltage:(V)	-1.17	-0.90
<i>a</i> ₀	0.06634	0.03627
a_l	0.01835	0.06445
a_2/a_1	-1.555	0.131
a_3/a_1	1.215	-0.359
a_4/a_1	0.403	-0.045
a5/a1	-0.472	0.106

REFERENCES

[1] Y. C. Lin, E. Y. Chang, H. Yamaguchi, Y. Hirayama, X. Y. Chang, and C. Y. Chang, "Device linearity comparison of uniformly doped and δ-doped In_{0.52}Al_{0.48}As/In_{0.6}Ga_{0.4}As metamorphic HEMTs," *IEEE Electron Device Lett.*, vol. 27, no. 7, pp. 535–537, Jul. 2006.

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Y. C. Lin, E. Y. Chang, and X. Y. Chang are with the Department of Materials Science and Engineering and Microelectronics and Information Systems Research Center, National Chiao Tung University, Hsinchu 30010, Taiwan, R.O.C. (e-mail: edc@mail.nctu.edu.tw).

H. Yamaguchi and Y. Hirayama are with NTT Basic Research Laboratories, Atsugi 243-0198, Japan.

C. Y. Chang is with the Department of Electronics Engineering, National Chiao Tung University, Hsinchu 30010, Taiwan, R.O.C.

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